

# ISO/TR 22335:2007-07 (E)

## Surface chemical analysis - Depth profiling - Measurement of sputtering rate: mesh-re plica method using a mechanical stylus profilometer

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Contents	Page
Foreword .....	iv
Introduction .....	v
1 Scope .....	1
2 Terms and definitions .....	1
3 Symbols and abbreviated terms .....	2
4 Principle .....	2
5 Procedure .....	2
5.1 Generating the replica pattern .....	2
5.2 Measurement of sputtered crater depth using a stylus profilometer .....	8
5.3 Estimation of sputtering rate .....	11
6 Summary of round-robin results .....	11
Annex A (informative) Geometry of specimen surface and ion gun .....	12
Annex B (informative) Dependance of replica patterns on mesh-opening size .....	15
Bibliography .....	18